



**PATENT**

Atty. Dkt. No. APPM/008461/PPC/ECP/CKIM

1 FW

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
Yi-Chiau Huang

Serial No.: 10/774,194

Confirmation No.: 6951

Filed: February 5, 2004

**For: METHOD AND APPARATUS  
FOR INFILM DEFECT  
REDUCTION FOR  
ELECTROCHEMICAL COPPER  
DEPOSITION**

**MAIL STOP AMENDMENT**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Group Art Unit: 2823

Examiner: Quovaunda Jefferson

<p><b>CERTIFICATE OF MAILING</b></p> <p><b>37 CFR 1.8</b></p> <p>I hereby certify that this correspondence is being deposited on  <u>November 4, 2005</u>, with the United States Postal Service as  First Class Mail in an envelope addressed to: Mail Stop  Amendment, Commissioner for Patents, P.O. Box 1450,  Alexandria, VA 22313-1450.</p> <p><u>November 4, 2005</u></p> <p>Date</p> <p><u>Kurt R. Torkin</u></p> <p>Signature</p>
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## **RESPONSE TO OFFICE ACTION DATED AUGUST 23, 2005**

In response to the Office Action dated August 23, 2005, having a shortened statutory period for response set to expire on November 23, 2005, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008461/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Specification** begin on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper. **Remarks** begin on page 7 of this paper.